# Intermediate temperature oxidation in silicon nitride yttria ceramics

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Silicon nitride billets with both 4% and 8%  $Y_2O_3$  additives have been subjected to oxidation treatments for up to 300 h, in air, in the temperature range 700 to 1000° C. Flexure strength and weight gain measurements together with both scanning and transmission electron microscopy and X-ray diffraction studies were conducted on these billets in an effort to understand the oxidation process. It appears that the degradation phenomena is associated with both the formation of phases outside the Si<sub>3</sub>N<sub>4</sub>-Si<sub>2</sub>ON<sub>2</sub>-Y<sub>2</sub>Si<sub>2</sub>O<sub>7</sub> compatibility triangle of the system Si<sub>3</sub>N<sub>4</sub>-SiO<sub>2</sub>-Y<sub>2</sub>O<sub>3</sub> and with the decomposition of W-containing phases at and near the grain boundaries.

# 1. Introduction

Oxidation of  $Si_3N_4$  has been shown to occur in the presence of both high and low oxygen partial pressure. At high oxygen partial pressures and temperatures over 1000°C, a dense oxide layer forms sealing off all surface pores. Weight gained during this process follows a parabolic law as a function of time [1]. While at low oxygen partial pressures,  $< 8 \times 10^{-4}$  atm, an active oxidation process characterized by weight loss due to the formation of gaseous  $SiO_2$  takes place [2]. Lange et al. [3] discovered that  $Si_3N_4$  compositions containing high concentrations of Y2O3, 8% and higher, suffer severe property degradation when exposed to air for long periods of time at intermediate temperatures, < 1000° C. They attributed this phenomenon to the large change in molar volume associated with the formation of phases, and their oxidation products, which are outside the so-called compatibility triangle  $Si_3N_4$ - $Si_2ON_2$ - $Y_2Si_2O_7$  of the system  $Si_3N_4$ -SiO<sub>2</sub>-Y<sub>2</sub>O<sub>3</sub>. Gazza [4], however, indicated that phase instabilities and resultant crack formation were not always found in oxidized Si<sub>3</sub>N<sub>4</sub> containing quaternary oxynitrides. Mangles and Bar [5] showed that for optimum intermediate temperature oxidation resistance in the range 700 to 1000°C, the presence of only one single phase at the grain boundaries of  $Si_3N_4$ , namely  $Y_2Si_2O_7$ , is essential. Their patent clearly demonstrates that both the temperature and nitrogen gas pressure of the final sintering cycles of RBSN (with  $Y_2O_3$  additives), as well as the encapsulating powder mixtures of BN, Si<sub>3</sub>N<sub>4</sub>, SiO<sub>2</sub> and Y<sub>2</sub>O<sub>3</sub>, are critical to the process of achieving a thermally stable, single phase or phases at the grain boundaries. Apparently higher SiO<sub>2</sub> content of the encapsulating powder mixture, 15% to 25% by weight, helps the formation of  $Y_2Si_2O_7$  single phase thus resulting in better oxidation resistance. However, according to Arias [6] at NASA, the presence of  $SiO_2$  at levels higher than 11% by weight decreases the hightemperature strength of the sintered material. Work by Weaver and Lucek [7] at Norton shows that  $Si_3N_4$ disintegrates after intermediate temperature oxidation for yttria content 8% and higher. Lucek [8] showed that those  $Si_3N_4$  billets with 8%  $Y_2O_3$  do not show loss of strength after exposure at 900 and 1000° C. Govila *et al.* [9] found that an  $Si_3N_4 + 8\% Y_2O_3$ , which suffers accelerated weight gain at 1000° C, but only around 10% degradation in room-temperature strength after static oxidation for 300 h at 1000° C, nevertheless shows extreme sensitivity to early failure during stress rupture testing at 1000° C. At 1000° C and an applied stress of 138 MPa, failure times of the order of 50 h were observed. At 1200° C, and a stress of 344 MPa, no failures were observed after 260 h.

The literature shows a lack of agreement on the desirable  $Si_3N_4$  compositions needed to achieve good oxidation resistance; some researchers recommend limiting the  $Al_2O_3$  content to < 2% (Quackenbush [10] at GTE and Arias [6]), and SiO<sub>2</sub> to < 11.2% and C to < 0.2% (Gazza [4] at AMMRC and Schoun [11] at NASA).

The present investigation was conducted to determine the effect of yttria content on the intermediate temperature oxidation phenomena for  $Si_3N_4$  compositions within the compatibility triangle ( $Si_3N_4$ - $Si_2ON_2-Y_2Si_2O_7$ ) and to characterize the resulting microstructure in an effort to determine factors contributing to the degradation process.

# 2. Experimental procedure

Silicon nitride billets containing both 4% and 8%  $Y_2O_3$  were prepared by hot pressing. Standard Norton MOR bars, 0.125 in  $\times$  0.128 in  $\times$  2 in. ( $\sim$  0.32 cm  $\times$  0.325 cm  $\times$  5.08 cm) were machined from these billets for room-temperature four-point bend tests. The bend strength was measured using 1 in (2.54 cm) span quarter-point loading on samples in both the as-received and oxidized condition. Oxidation treatments were conducted in still air, in a resistance furnace. The test bars were placed on high-purity



Figure 1 Ternary-phase diagram of the system  $Si_3N_4-Y_2O_3-SiO_2$  showing the location of investigated compositions of billets A to F. Billet compositions are given in Table I.

 $Al_2O_3$  knife edges for the 700 to  $1000^{\circ}$  C exposures. Weight changes were determined using a Mettler microbalance with sensitivity down to 0.00003 g. Chemical analysis was conducted on those billets using atomic absorption and emission spectrophotometry; the results are shown in Table I. The oxygen content of these billets was determined, before oxidation, using the Leco equipment whereby oxygen is transformed to carbon dioxide and measured by infrared absorption and nitrogen gas by thermal conductivity. The oxygen content of the material is assumed to exist only in SiO<sub>2</sub> and Y<sub>2</sub>O<sub>3</sub>. Based on this assumption, the compositions of the various billets are located within the ternary system Si<sub>3</sub>N<sub>4</sub>-SiO<sub>2</sub>-Y<sub>2</sub>O<sub>3</sub> and are shown in Fig. 1.

The transmission electron microscopy work was performed on a Jeol 100C STEM equipped with a Kevex energy dispersive spectrometer. Thin sections were prepared by cutting  $Si_3N_4$  bars with a low-speed diamond saw to a thickness of 300  $\mu$ m. These sections were then ground on both 30 and 15  $\mu$ m metal-bonded diamond discs to a thickness of 90  $\mu$ m. Discs of 3 mm size were cut from the sections using an ultrasonic disc cutter. The discs were ion milled at 6 keV and 15° tilt using a Gatan ion-beam thinning system until a small hole perforated the sample. The foils were then coated with a thin layer of carbon to prevent charging in the microscope.

A Philips automated powder diffraction system, P1700, was utilized for the X-ray diffraction experiments. The Si<sub>3</sub> N<sub>4</sub> samples were ground with tungsten carbide balls in a spex mixer/mill and screened through a 325 mesh sieve prior to X-ray diffraction analysis. CuK $\alpha$  radiation was used to a generator setting of 40 kV, 40 mA, 0.1° divergence slit and 0.3° receiving slit and the diffracted beam collected by a proportional counter. The samples were scanned at a speed of 0.025 20 sec<sup>-1</sup> and step interval of 0.02°.

## 3. Results and observations

Table II and Figs 2 and 3 summarize some of the ambient-temperature flexure strengths (four-point bending); the individual data points on the graph are the average of eight tests. The weight gain is measured after 100 and 200 h exposure at 700° C for the tested  $Si_3N_4 + Y_2O_3$  billets. The  $Si_3N_4 + 4\%$   $Y_2O_3$  showed neither anomalous weight gains nor measurable strength reductions. Billet 1959 shows higher strength than that for billets 2755 and 2756 (Fig. 2), owing to its higher  $Y_2O_3$  content (5.54 wt %). The dramatic increase in the flexure strength of billet 1959 after

TABLE I Chemical analysis (wt %) of various Si<sub>3</sub>N<sub>4</sub> billets used in the investigation

Billet no. identification	O <sub>2</sub>	Y <sub>2</sub> O <sub>3</sub>	Fe	Al	W	С	N
1761	4.6 + 0.003	7.46	0.17	1.8	2.23	2.78	34.8
Α							
1959	3.6 + 0.06	4.4	0.16	0.14	2.36	2.38	36.7
В							
2755	3.2 + 0.01	3.43	0.03	0.05	4.31	1.90	35.7
С							
2756	3.4 + 0.09	3.35	0.25	0.21	4.00	2.17	35.3
D							
1546	3.9 + 0.06	6.50	0.22	0.17	2.63	2.45	34.7
E							
1974	4.2 + 0.03	5.54	-		2.36	-	35.2
F							



*Figure 2* Room-temperature flexture strength for Si<sub>3</sub>N<sub>4</sub> billets containing around 4% Y<sub>2</sub>O<sub>3</sub>, as a function of oxidation temperature and exposure time. Billet 1959 contains 5.54% Y<sub>2</sub>O<sub>3</sub>; billet 2755 has 3.71% Y<sub>2</sub>O<sub>3</sub> and billet 2756 3.35% Y<sub>2</sub>O<sub>3</sub>.

*Figure 3* Room-temperature flexture strength for Si<sub>3</sub>N<sub>4</sub> containing different amounts of Y<sub>2</sub>O<sub>3</sub>. Billet 1974 contains 9.41% Y<sub>2</sub>O<sub>3</sub>, while billet 1546 contains 6.55% Y<sub>2</sub>O<sub>3</sub> and billet 1761 has 10.52% Y<sub>2</sub>O<sub>3</sub>.

TABLE II Room-temperature strengths and weight gains after intermediate temperature oxidation of  $Si_3N_4$  containing different amounts of  $Y_2O_3$ 

Billet no.	Composition	Starting material	As-received MOR $\pm$ s.d.*	700° C exposure					
				100 h		200 h			
				$\overline{\text{MOR} \pm \text{s.d.}^{\dagger}}$	Wt gain (%)	$\overline{MOR \pm s. b.^{\dagger}}$	Wt gain (%)		
1959	4% Y <sub>2</sub> O <sub>3</sub>	N <sup>‡</sup> HN-26	111.9 ± 8.3	131.2 ± 5.1	0.012	126.7 ± 7.5	0.008		
2756	4% Y <sub>2</sub> O <sub>3</sub>	N HN-39	$78.5^{\$} \pm 6.3$	78.7 ± 7.5	0.003	83.0 ± 4.5	0.005		
2755	4% Y <sub>2</sub> O <sub>3</sub>	$\mathbf{K}^{\parallel}$	94.9 <sup>4</sup> ± 3.9	$90.3 \pm 3.0$	0.003	87.7 ± 18.0	0.005		
1546	8% Y <sub>2</sub> O <sub>3</sub>	N HN-20	131.1 ± 2.7	**	0.898	**	1.168		
1974	8% Y <sub>2</sub> O <sub>3</sub>	N HN-25	133.4 ± 11.6	111.7 ± 14.9	0.084	118.2 <u>+</u> 4.2	0.089		
1761	8% Y <sub>2</sub> O <sub>3</sub>	N HN-23	$123 \pm 3.5$	**	1.270	N/A	N/A		

\*Average of 8 breaks 10<sup>3</sup> p.s.i.

<sup>†</sup>Average of 4 breaks 10<sup>3</sup> p.s.i.

<sup>‡</sup>Norton standard HN series  $Si_3N_4$  powder.

§Test bar analysis: 0.21% Al; 0.25% Fe.

Kemanord high purity 95P Si<sub>3</sub>N<sub>4</sub> powder.

Test bar analysis: 0.05% Al; 0.03% Fe.

\*\* Too oxidized and cracked to test.

TABLE III	Phase analysis of	various Si <sub>3</sub> N <sub>4</sub> pha	es before and after	oxidation treatment	using X-ray diffraction	on techniques

	$\beta$ -Si <sub>3</sub> N <sub>4</sub>	WSi <sub>2</sub>	WC	Si <sub>2</sub> ON <sub>2</sub>	$Y_2Si_2O_7$	$Y_5 N(SiO_4)_3$	SiO <sub>2</sub>
Billets with 4% Y <sub>2</sub> O <sub>3</sub>					<u> </u>	· · · · · · · · · · · · · · · · · · ·	
1959 unoxidized	major	minor	trace	_	minor	-	-
1959 700° C 100 h	major	minor	trace	trace	minor	_	-
2755 unoxidized	major	-	minor	minor	trace	-	
2755 700° C 100 h	major	-	minor	minor	minor	-	
2756 unoxidized	major	_	minor	minor	trace	_	-
2756 700° C 100 h	major	-	minor	minor	minor	_	-
2756 700° C 100 h	major	minor	trace	-	-	minor	-
discoloured area							
Billets with 8% Y <sub>2</sub> O <sub>3</sub>							
1546 unoxidized	major	minor	trace	_	-	minor	_
1546 700° C 100 h	major	_	trace	-	-	minor	-
catastrophic failure	-						
1546 700° C 100 h	major	minor	trace	-	-	minor	-
1761 unoxidized	major	minor	trace	-	-	minor	-
1761 700° C 100 h	major	trace	trace	-	-	minor	
catastrophic failure							
1974 unoxidized	major	minor	-	-	-	minor	-
1974 700° C 100 h	major	minor	-	-	-	minor	minor



Figure 4 Disintegration of test bars of Si<sub>3</sub>N<sub>4</sub> containing 8%  $Y_2O_3$  as a result of oxidation treatment at various temperatures and times. (a) 100 h at a 1000° C, b 800° C, c 700° C, d 500° C, e unexposed. (b) 700° C, a unexposed, b 100 h, c 100 h, d 200 h, e 200 h.



Figure 5  $Si_3N_4 + 4\% Y_2O_3$  test bars showing no disintegration after oxidation in air at 700° C for up to 200 h. a unexposed, b, c, e 100 h, d, f 200 h.

exposure to  $700^{\circ}$  C oxidation is not within the experimental scatter and may be caused by a stress anneal (healing) of surface-grinding damage of the MOR bars.

All the billets with 8 %  $Y_2O_3$ , showed significant weight gains but only two showed severe strength reductions, billets 1761 and 1546. Bars made from those billets disintegrated completely after exposure to both 700 and 800°C in air, see Fig. 4. On the other hand, bars made with 4 %  $Y_2O_3$  did not crack, Fig. 5. After both the 700 and 800°C exposure, some bars of billet 2756 containing 4 %  $Y_2O_3$  showed discoloration (white coating) on the surface — see Fig. 6. Both energy dispersive X-ray microanalysis (EDAX), Fig. 6, and X-ray photoelectron spectroscopy (ESCA) analysis, Fig. 7, reveal that those areas are rich in SiO<sub>2</sub>.



Figure 6 Discoloration of the surface of  $Si_3N_4$  bars as a result of oxidation at 800° C for 100 h. In addition to discoloration, billet 1761 has disintegrated, while billet 2756 did not.



Figure 7 X-ray photoelectron spectroscopy analysis of discoloured regions on the surface of oxidized  $Si_3N_4$ .



Figure 8 Scanning electron micrographs of the fracture surface of  $Si_3N_4$  containing both (a) 4%  $Y_2O_3$  (billet 1974) and (b) 8%  $Y_2O_3$  (billet 1761) after oxidation treatment. Extensive grain-boundary cracking can be observed in billet 1761.



Figure 9 A transmission electron micrograph of  $Si_3N_4$  with 8%  $Y_2O_3$  (billet 1975) showing a broad size distribution of the betaphase grains.

#### 3.1. Scanning electron microscopy

The fracture surface of the  $Si_3N_4 + 8\% Y_2O_3$  material which underwent severe degradation shows extensive grain-boundary cracking, which was absent in those samples which did not degrade, see Fig. 8. The lower yttria content compositions show a mix of intergranular and transgranular failure.

#### 3.2. Transmission electron microscopy

Bright-field images of unoxidized samples show polygonized beta Si<sub>3</sub>N<sub>4</sub> grains with a wide size distribution, see Fig. 9, surrounded by a number of grainboundary phases rich in both tungsten and yttrium. Dark-field images show the presence of a thin glassy film at the  $\beta$ -Si<sub>3</sub>N<sub>4</sub> boundaries of all compositions examined, an example is given in Fig. 10. This has also been documented in the literature by other investigators [12]. Samples with 8% Y<sub>2</sub>O<sub>3</sub> show the presence of  $Y_5N$  (SiO<sub>4</sub>)<sub>3</sub> at the grain boundaries, as confirmed from electron diffraction patterns, see Fig. 11. Extensive substructural changes have also been observed at and near the grain boundaries of Si<sub>3</sub>N<sub>4</sub> as a result of oxidation, see Fig. 11, indicating that numerous thermochemical reactions are taking place during the process. The tungsten-containing phases at the  $\beta$ -Si<sub>3</sub>N<sub>4</sub> boundaries were identified, from X-ray diffraction, to be WSi<sub>2</sub> and WC, see Fig. 12.

#### 3.3. X-ray diffraction

A summary of the X-ray diffraction study conducted on Si<sub>3</sub>N<sub>4</sub> is shown in Table III. Samples with 4% Y<sub>2</sub>O<sub>3</sub> show the presence of  $\beta$ -Si<sub>3</sub>N<sub>4</sub> as the major phase with minor and trace amounts of other phases including Si<sub>2</sub>ON<sub>2</sub>, Y<sub>2</sub>Si<sub>2</sub>O<sub>7</sub>, WC and WSi<sub>2</sub>. These silicon oxynitride phases lie within the compatibility triangle of the ternary Si<sub>3</sub>N<sub>4</sub>–SiO<sub>2</sub>–Y<sub>2</sub>O<sub>3</sub> system. No phases outside this triangle have been detected in those samples after they were oxidized. On the other hand, Si<sub>3</sub>N<sub>4</sub> compositions containing 8% Y<sub>2</sub>O<sub>3</sub> have been detected, in addition to  $\beta$ –Si<sub>3</sub>N<sub>4</sub>, WC, WSi<sub>2</sub> and Y<sub>5</sub>N (SiO<sub>4</sub>)<sub>3</sub> in both the oxidized and non-oxidized state. The presence of Y<sub>5</sub>N (SiO<sub>4</sub>)<sub>3</sub>, which lies outside the compatibility triangle, has been confirmed by selected-area diffraction, see Fig. 11.

Those compositions containing 8% Y<sub>2</sub>O<sub>3</sub>, which suffered intermediate temperature oxidation failure show the absence of WSi<sub>2</sub> which existed in the original hot-pressed billets, see Fig. 12. X-ray analysis did not reveal the presence of WO<sub>3</sub> as an oxidation product in those samples.

## 4. Discussion

The data presented so far clearly indicate that  $Si_3 N_4$ material containing 8%  $Y_2O_3$  is thermally unstable in the temperature range 700 to 1000°C, while material with 4% Y<sub>2</sub>O<sub>3</sub> does not suffer from the same phenomenon. This instability is apparently related to two major observable differences between these two compositions. The first is the fact that tungstencontaining phases, namely WSi2 and WC in the 8%  $Y_2O_3$  material which failed catastrophically (billet 1546 as an example), have severely decomposed; most of those tungsten-containing phases existed at the  $\beta$ -Si<sub>3</sub>N<sub>4</sub> grain boundaries. Scanning electron microscopy shows that the predominant mode of failure of these compositions is intergranular in nature, see Fig. 8. This may indicate that the process of decomposition of tungsten-containing grainboundary phases introduce stresses high enough to cause cracking and separation. The second difference



Figure 10 A pair of (a) bright- and (b) dark-field micrographs of billet 1959 which was oxidized in air for 100 h at 1000°C showing the presence of an amorphous phase at the grain boundary of hot-pressed  $Si_3N_4$ .



Figure 11 Electron diffraction of  $Si_3N_4$  samples with 8%  $Y_2O_3$  showing the presence of  $Y_5N$  ( $SiO_4$ )<sub>3</sub> phase at the grain boundaries.

between 4%  $Y_2O_3$  material and the 8%  $Y_2O_3$  is the presence of  $Y_5N$  (SiO<sub>4</sub>)<sub>3</sub> phase in those billets with the higher  $Y_2O_3$  content. This phase lies outside the so-called thermally stable region, i.e. Si<sub>3</sub>N<sub>4</sub>-Si<sub>2</sub>ON<sub>2</sub>- $Y_2Si_2O_7$  triangle of the ternary system Si<sub>3</sub>N<sub>4</sub>-SiO<sub>2</sub>- $Y_2O_3$ . Although no experiment has yet been designed to measure the volume change/residual stresses introduced during formation and/or decomposition of those undesirable phases (outside the compatibility region), Lange and others postulated that this is the main reason for the material's catastrophic failure at intermediate temperatures. The fact that significant substructural changes have been observed at and near the 8%  $Y_2O_3$  material's grain boundaries as a result of oxidation indicate that Lange's explanation is not sufficient, because some of these undesirable phases



*Figure 12* X-ray diffraction pattern of billet 1546 (8%  $Y_2O_3$ ) showing the effect of oxidation on the stability of WSi<sub>2</sub>. (. . .) 1546 unoxidized; (----) 1546, 700° C, 100 h; (----) 1546, 700° C, 100 h; catastrophic failure.

existed in some billets that did not fail. More work is needed to reveal intricate substructural changes at the material's grain boundaries after oxidation using compositional line profile and diffusion studies to help quantify those microstructural changes in relationship to the oxidation process.

## 5. Conclusions

1.  $Si_3N_4$  compositions containing 4%  $Y_2O_3$  did not undergo the degradation effects observed in the 8%  $Y_2O_3$  material during oxidation at 500 to 1000°C.

2. The material with the 4%  $Y_2O_3$  contains the phases  $Si_2ON_2$ ,  $Y_2Si_2O_7$ , and  $\beta$ -Si<sub>3</sub>N<sub>4</sub> which are within the compatibility triangle. On the other hand, the material with 8%  $Y_2O_3$  contains  $Y_5N(SiO_4)_3$  which is outside the triangle.

3. The oxidation process resulted in decomposition and disappearance of  $WSi_2$  from the grain boundaries of  $Si_3N_4$  with 8%  $Y_2O_3$  which underwent severe cracking.

4. Transmission electron microscopy work reveals the presence of substructural features at and near the boundaries of oxidized  $\beta$ -Si<sub>3</sub>N<sub>4</sub> grains; those features did not exist in the non-oxidized material.

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